

Totally Depleted Silicon Surface Barrier Detectors

Main Application: Particle identification, telescopes of detectors, any type of ΔE measurements. In addition to $\Delta E/\Delta x$ experiments, the uniformly high field of B Series detectors makes them the best choice for rise-time discrimination or for precision timing experiments. These detectors are also useful in any experiment where an A Series detectors is used; B Series detectors are preferable if radiation damage is likely.

Supplied with T Mount unless otherwise specified.

Active Area (mm ²)	Guaranteed Maximum Resolution (keV)**		Depletion Depth 150 μm Range: 125–175 μm	Depletion Depth 200 μm Range: 176–225 μm	Depletion Depth 250 μm Range: 226–275 μm	Depletion Depth 300 μm Range: 276–350 μm	Depletion Depth 400 μm Range: 351–450 μm
	α	β	Model No.	Model No.	Model No.	Model No.	Model No.
50	15	6	B-015-050-150	B-015-050-200	B-015-050-250	B-015-050-300	B-015-050-400
	16	7	B-016-050-150	B-016-050-200	B-016-050-250	B-016-050-300	B-016-050-400
150	17	9	B-017-150-150	B-017-150-200	B-017-150-250	B-017-150-300	B-017-150-400
	18	10	B-018-150-150	B-018-150-200	B-018-150-250	B-018-150-300	B-018-150-400
300	19	12	B-019-300-150	B-019-300-200	B-019-300-250	B-019-300-300	B-019-300-400
	20	15	B-020-300-150	B-020-300-200	B-020-300-250	B-020-300-300	B-020-300-400
450	23	17	B-023-450-150	B-023-450-200	B-023-450-250	B-023-450-300	B-023-450-400
	24	19	B-024-450-150	B-024-450-200	B-024-450-250	B-024-450-300	B-024-450-400

Active Area (mm ²)	Guaranteed Maximum Resolution (keV)**		Depletion Depth 500 μm Range: 451–550 μm	Depletion Depth 700 μm Range: 650–750 μm	Depletion Depth 1000 μm Range: 950–1050 μm	Guaranteed Maximum Resolution (keV)**		Depletion Depth 1500 μm § Range: 1450–1550 μm
	α	β	Model No.	Model No.	Model No.	α	β	Model No.
50	15	8	B-015-050-500	B-015-050-700	B-015-050-1000	17	12	B-017-050-1500
	16	9	B-016-050-500	B-016-050-700	B-016-050-1000	19	14	B-019-050-1500
150	17	9	B-017-150-500	B-017-150-700	B-017-150-1000	19	14	B-019-150-1500
	18	10	B-018-150-500	B-018-150-700	B-018-150-1000	21	16	B-021-150-1500
300	19	13	B-019-300-500	B-019-300-700	B-019-300-1000	21	16	B-021-300-1500
	20	14	B-020-300-500	B-020-300-700	B-020-300-1000			
450	21	16	B-021-450-500	B-021-450-700	B-021-450-1000	24	19	B-024-450-1500
	23	18	B-023-450-500	B-023-450-700	B-023-450-1000			

Active Area (mm ²)	Guaranteed Maximum Resolution (keV)**		Depletion Depth 2000 μm § Range: 1950–2050 μm
	α	β	Model No.
50	18	13	B-018-050-2000
150	20	15	B-020-150-2000
300	23	18	B-023-300-2000
450	26	21	B-026-450-2000

* All standard totally depleted detectors are cut off-axis from the parent crystal at a specific angle that will minimize ion channeling. Supplied in T Mount unless specified otherwise by appropriate letter prefix. Other areas and depths available on special order.

** First three digits of Model No. indicate total system resolution FWHM for ²⁴¹Am, 5.486-MeV alphas, using standard ORTEC electronics and 0.5- μs shaping time constants. Beta resolution approximated by pulser width FWHM.

§ Requires special order.

B Series

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Mounting Arrangements

A This is a "ring mount"; i.e., the silicon wafer is offered on its ring without output connectors. This infrequently used arrangement is available on special request.

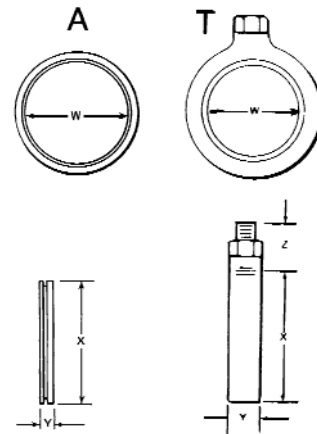
T Microdot on the side of the can; without adjustable screws. (Open back.)

Dimensions are given in millimeters.

§ Built into a Microdot connector only.

For detectors 1500 or 2000 μm deep, add 1.5 mm to the Y dimension.

Detector Size (mm ²)	W (Nominal)	Type A Mount		Type T § Transmission Mount		
		X	Y	X	Y	Z
050	8.0	15.2	3.7	19.4	7.9	9.9
150	13.8	22.0	3.7	26.1	7.9	9.9
300	19.5	27.1	3.7	31.6	7.9	9.9
450	23.9	30.5	3.7	34.8	7.9	9.9
Tol.	± 0.5	± 0.3	± 0.3	± 0.3	± 0.3	± 0.3



Specifications subject to change
052412

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